A PHOTOSENSITIVE POLYMER CONTAINING SILICON AND A RESIST COMPOSITION USING THE SAME

ABSTRACT OF THE DISCLOSURE

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A photosensitive polymer including silicon and a resist composition using the same are disclosed. The photosensitive polymer has the following formula 1.

<Formula 1>

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In formula 1, R_1 of the first monomer and R_3 of the third monomer are an alkyl group. R_2 of the first monomer is hydrogen, alkyl, alkoxy, or carbonyl. The X of the first monomer is an integer selected from 1 to 4. Further, m/(m+n+p) is about 0.1 to about 0.4, n/(m+n+p) is about 0.1 to about 0.5, and p/(m+n+p) is about 0.1 to about 0.4.

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